

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Maloney, et al.

Serial No.  
Filed:

To be assigned  
herewith


Atty. Docket No. A-68359-1/RMA

**Apparatus And Method For Chemical  
Mechanical Polishing (CMP) Head Having  
Direct Pneumatic Wafer Polishing Pressure**

EXPRESS MAIL<sup>®</sup> MAILING LABEL  
NUMBER EL 758 643 060 US

DATE OF DEPOSIT: December 21, 2001  
I HEREBY CERTIFY THAT THIS PAPER OR FEE IS BEING  
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By

  
Darryl Kriner

#2  
10/027935  
jc675 U.S. PTO  
5/28/02

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents  
Washington D.C. 20231

Sir:


Applicant hereby submits patents, publications, or other information of which he is aware, which he believes may be material to the examination of the above referenced application and in respect to which there may be a duty to disclose in accordance with 37 C.F.R. §1.56. The disclosure contained herein is not intended to constitute an admission that any patent, publication, or other information referred to is "prior art" for this invention unless specifically designated as such. In accordance with 37 C.F.R. §1.97 (b), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined by 37 C.F.R. §1.56 exists.

The references cited herein were cited in the parent application Serial No. 09/390,142 filed September 3, 1999 and therefore copies of the references are not provided. No fee is due.

Respectfully submitted,

FLEHR HOHBACH TEST  
ALBRITTON & HERBERT LLP

By

  
R. Michael Ananian, Reg. No. 35,050

4 Embarcadero Center, Suite 3400  
San Francisco, CA 94111-4187  
Telephone : (650) 494-8700

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# INFORMATION DISCLOSURE CITATION

PTO-1449

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A-68359-1/RMA

SERIAL NO.

APPLICANT  
Maloney, et al.

FILING DATE

GROUP

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EXAMINER

DATE CONSIDERED